AD-R191 248 THIN FILM RESEARCH DIAGNOSTICS INSTRUMENTATION(U) NEW 1/1
MEXICO UNIV ALBUQUERQUE MCNEIL 21 OCT 87
AFOSR-TR-87-1757 AFOSR-85-0091 F/G 7/2 NL



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REPORT DOCUMENTATION PAGE 16. RESTRICTIVE MARKINGS UNCLASSIFIED 28 SECURITY CLASSIFICATION AUTHO 3. DISTRIBUTION/AVAILABILITY OF REPORT Approved for public release; distribution unlimited. 26 DECLASSIFICATION DOWNG 4 PERFORMING ORGANIZATION 64. NAME OF PERFORMING ORGANIZATION B. OFFICE SYMBOL 7a. NAME OF MONITORING ORGANIZATION elf applicable) AFOSR University of New Mexico 7b. ADDRESS (City, State and ZIP Code) 6c. ADDRESS (City, State and ZIP Code) Bldg 410 EECE Building, Rm 125 Albuquerque, NM Bolling AFB, DC 20332-6448 Sa. NAME OF FUNDING/SPONSORING 86. OFFICE SYMBOL 9. PROCUREMENT INSTRUMENT IDENTIFICATION NUMBER ORGANIZATION (If applicable) AFOSR-85-0091 Same as 7a NE Bc. ADDRESS (City, State and ZIP Code) 10. SOURCE OF FUNDING NOS. PROGRAM PROJECT TASK WORK UNIT ELEMENT NO. Same as 7b NO. NO. NO 11 TITLE Include Security Classification Thin Film Research 61102F 2917 A3 Diagnostics Instrumentation 12. PERSONAL AUTHOR(S) 134 TYPE OF REPORT 13b. TIME COVERED 14 DATE OF REPORT (Yr. Mo., Day) 15 PAGE COUNT Final FROM 01-01-85 to 6/30/86 87-10-21 16. SUPPLEMENTARY NOTATION COSATI CODES 17 18. SUBJECT TERMS (Continue on reverse if necessary and identify by bloc imberi FIELD GROUP SUB. GR 19. ABSTRACT (Continue on reverse if necessary and identify by block number) All equipment purchased under this contract has been used in the Thin Film Laboratory for deposition and analysis of thin films. In particular, the Ar-ion laser is being used to investigate film scatter at multiple wavelengths. The excimer laser is being used to enhance deposition mechanisms; it illuminates a coated surface throughout film disposition. The microscope and ellipsometer are part of diagnostics used to analyze films. 20. DISTRIBUTION/AVAILABILITY OF ABSTRACT 21. ABSTRACT SECURITY CLASSIFICATION UNCLASSIFIED UNCLASSIFIED/UNLIMITED 🔯 SAME AS RPT 🚍 DTIC USERS 🗔 22a, NAME OF RESPONSIBLE INDIVIDUAL 22b TELEPHONE NUMBER (Include Area Code) 22c. OFFICE SYMBOL CAPTAIN MALLOY 202/767-4931 NE

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University of New Mexico

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Progress:

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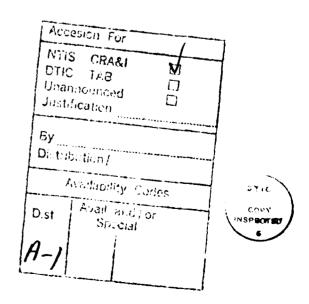
## FINAL REPORT FOR AFOSR CONTRACT #85-0091

Equipment purchased under this contract in support of thin film research includes the following:

Ellipsometer package	\$ 27,000
Ar-ion laser package	28.000
Nomarski Microscope	15,801
Excimer laser package	50,000
TOTAL	\$120,801
UNM Matching	\$ 26,133
AFOSR Portion	\$ 94,668

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